

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Renken et al.

Title: Process Condition Sensing Wafer and Data Analysis System

Application No.: 10/685,550 Filing Date: October 14, 2003

Examiner: Samir M. Shah Group Art Unit: 2856

Docket No.: SENS.005US1 Conf. No.: 4924

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Mail Stop RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**REQUEST FOR CONTINUED EXAMINATION (RCE)**

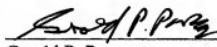
Dear Sir:

This is a Request for Continued Examination (RCE) under 37 C.F.R. § 1.114 of the above-identified application. Please consider the Response to Office Action and amendment, which is being filed herewith.

The RCE fee of \$790.00 required under 37 C.F.R. § 1.17(e) has been authorized via EFS to Deposit Account 04-0258. The Commissioner is hereby authorized to charge any additional fees, which may be required, or credit any overpayment to Deposit Account 04-0258. Please contact the undersigned with any questions concerning this request or the above-identified patent application.

**FILED VIA EFS**

Respectfully submitted,

  
Gerald P. Parsons  
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6/29/07  
Date

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